



Japan Micropatterning Committee Meeting Summary and Minutes

SEMI Japan Standards Summer 2013 Meetings

Wednesday, August 28, 2013 15:30-17:30

SEMI Japan, Tokyo, Japan

Next Committee Meeting

SEMI Japan Standards Winter 2013 Meetings

Wednesday, December 11, 2013, 15:30-17:00

SEMI Japan, Tokyo, Japan

Table 1 Meeting Attendees

Co-Chairs: Morihisa Hoga (Dai Nippon Printing)

SEMI Staff: Naoko Tejima (SEMI Japan)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Dai Nippon Printing	Hoga	Morihisa	Dai Nippon Printing	Suzuki	Toshio
-	Otaki	Masao	SEMI Japan	Tejima	Naoko

** alphabetical order by last name*

Table 2 Leadership Changes

<i>Group</i>	<i>Previous Leader</i>	<i>New Leader</i>
JA Micropatterning Committee Co-chairs	Open	Morihisa Hoga (Dai Nippon Printing)
5 year Review Task Force	Open	Morihisa Hoga (Dai Nippon Printing)

Table 3 Ballot Results

None

Table 4 Authorized Activities

None

Table 5 New Action Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
MP120828-1	Mask Data Format for Mask Tools Task Force	To prepare the information (blue) ballot of Doc. 5229, Revision to SEMI P44, as soon as possible.
MP120828-2	5 Year Review Task Force	To draft the document of Doc. 5484, Revision to SEMI P22-0307 to submit it for the earliest possible cycle.
MP121211-1	5 Year Review Task Force	To draft the document of Doc. 5537, Line Item Revision to SEMI P23-0200 to submit it for the earliest possible cycle.
MP130828-1	Masao Otaki	To draft the background statements for the Document #5484 and #5537.
MP130828-2	SEMI staff	To report the leadership change to JRSC on August 29.
MP130828-3	Morihisa Hoga	To check the proof of P35 and P36 for publication.
MP130828-4	SEMI staff	To change the document status of SEMI P20-0703 to “Inactive”.
MP130828-5	Toshio Suzuki	To check the detail of the proposal about the standardization of the 3D format.

1 Welcome, Reminders and Introductions

Morihisa Hoga, committee co-chair, called the meeting to order at 15:30. Self-introductions were made followed by the agenda review.

2 Leadership Change

Morihisa Hoga (Dainippon Printing) was appointed as co-chair of Japan Micropatterning Committee in succession to Iwao Higashikawa (ex Toshiba) who stepped down as it at the last committee meeting (April 9).

Action Item: SEMI staff to report the leadership change to JRSC on August 29.

3 Required Meeting Elements

The meeting reminders on program membership requirement, antitrust issues, intellectual property issues and international effective meeting guidelines, were reviewed by SEMI staff, Naoko Tejima.

4 Review of Previous Meeting Minutes

The committee reviewed the minutes of the previous meeting held on April 9, 2013.

Motion: To approve the minutes of the previous meeting as written.

By / 2nd: Masako Otaki (-) / Toshio Suzuki (Dainippon Printing)

Discussion: None

Vote: 2 in favor and 0 opposed. **Motion passed.**

Attachment: 01_JA_Micropatterning_Previous_Mtg_Minutes_130828

5 SEMI Staff Report

Naoko Tejima gave the SEMI staff report. This report included SEMI Global 2013 Calendar of Events, Global Standards Meeting Schedule, 2013 Critical Dates for SEMI Standards Ballots, SEMI Standards Publication, SEMICON Japan 2013 Information and Contact Information.

Attachment: 02_SEMI_Staff_Report_130828

6 Liaison Reports

6.1 North America Microlithography Committee Report

Naoko Tejima briefly reported for the North America Microlithography Committee. This report included Task Force and Leadership Changes, Leadership, Current Committees Structure, Meeting Information, Document Review Summary, New Activities, Task Force Updates, Five-year Review Update at SEMICON West and Contact Information.

Attachment: 03_NA_Microlithography_Comm_Report_130828

7 Task Force Reports

7.1 Mask Data Format for Mask Tools Task Force

Toshio Suzuki reported for the Mask data Format for Mask Tools Task Force. Of note:

- Task Force is working for *Doc. 5229, Revision to SEMI P44, Specification for Open Artwork System Interchange Standard (OASIS) Specific to Mask Tools*
- TF meeting will be held in September.
- The Information Ballot will be issued prior to the Letter Ballot issuing.

7.2 5 Year Review Task Force

7.2.1 Morihisa Hoga (Dainippon Printing) was appointed as a new co-leader of *5 Year Review Task Force* in succession to Iwao Higashikawa (ex Toshiba) who stepped down as it at the last committee meeting (April 9).

Motion: To approve to change the TF leader to Morihisa Hoga
By / 2nd: Masako Otaki (-) / Toshio Suzuki (Dainippon Printing)
Discussion: None
Vote: 2 in favor and 0 opposed. **Motion passed.**

7.2.2 Masao Otaki reported on progress for the 5 Year Review Task Force. Of note:

- TF is drafting the document of *Doc.5484, "Revision to SEMI P22-0307, Guideline for Photomask Defect Classification and Size Definition"* and is planning to submit the letter ballot for the earliest possible cycle.
- TF is drafting the document of *Doc.5537, "Line Item Revision to SEMI P23-0200 (Reapproved 1107), Guidelines for Programmed Defect Masks and Benchmark Procedures for Sensitivity Analysis of Mask Defect Inspection Systems"* and is planning to submit the letter ballot for the earliest possible cycle.
- Will work for the background statements for the both documents.

Action Item: Masao Otaki to draft the background statements for the Document #5484 and #5537.

Action Item: Morihisa Hoga to check the proof of P35 and P36 for publication.

7.2.3 Naoko Tejima reported the documents subject to 5-year review.

- SEMI P20-0703, Guideline for Catalog Publication of EB Resist Parameters (Proposal).
- This document has been already out of date, and should be changed the status to inactive.

Motion: To approve to change the document status of SEMI P20-0703 to "Inactive".
By / 2nd: Toshio Suzuki (Dainippon Printing) / Masako Otaki (-)
Discussion: None
Vote: 2 in favor and 0 opposed. **Motion passed.**

Action Item: SEMI staff to change the document status of SEMI P20-0703 to "Inactive".

8 Old Business

8.1 Previous Meeting Action Items

Naoko Tejima reviewed the previous meeting action items.

Table 6 Previous Meeting Actions Items

<i>Item #</i>	<i>Assigned to</i>	<i>Details</i>
MP120828-1	Mask Data Format for Mask Tools Task Force	To prepare the information (blue) ballot of Doc. 5229, Revision to SEMI P44, as soon as possible ... Open
MP120828-2	5 Year Review Task Force	To draft the document of Doc. 5484, Revision to SEMI P22-0307 to submit it for the earliest possible cycle, 2013 ... Open
MP121211-1	5 Year Review Task Force	To draft the document of Doc. 5537, Line Item Revision to SEMI P23-0200 to submit it for the earliest possible cycle, 2013 ... Open
MP130409-1	Suzuki Toshio	To try to find a candidate of co-chair in his office ... Close
MP130409-2	SEMI	To forward adjudication result of Doc.5535 to the ISC A&R Subcommittee for procedural review ... Close
MP130409-3	SEMI	To forward adjudication result of Doc.5536 to the ISC A&R Subcommittee for procedural review ... Close

9 New Business

None

10 Action Item Review

10.1 New Action Items

Naoko Tejima reviewed the new action items. These can be found in the New Action Items table at the beginning of these minutes.

11 Next Meeting and Adjournment

The next meeting of the Japan Micropatterning Committee is scheduled for Wednesday, December 11, 2013 15:30-17:00, at SEMI Japan, Tokyo, Japan.



Respectfully submitted by:
Naoko Tejima
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SEMI Japan
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Minutes approved by:

Morihisa Hoga (Dai Nippon Printing), Co-chair	October 1, 2013
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Table 7 Index of Available Attachments ^{#1}

#	<i>Title</i>
1	JA_Micropatterning_Previous_Mtg_Minutes_130828
2	SEMI_Staff_Report_130828
3	NA_Microlithography_Comm_Report_130828

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact Naoko Tejima at the contact information above.